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**In re United States Patent Application of:**

**Applicants:** Thomas H. Baum, et al.

**Group Art Unit:** 1621

**Serial No:** 09/945,831

**Examiner:** Nazario Gonzalez,  
Porfirio

**Date Filed:** September 18, 2001

**Confirmation No.:** 8827

**Title:** Source Reagent Compositions for CVD  
Formation of Gate Dielectric Thin Films Using Amide  
Precursors and Method of Using Same

**Customer No.:** 25559

**FACSIMILE TRANSMISSION CERTIFICATE**

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Maggie Chappuis  
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August 26, 2004  
Date of Transmission

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**AMENDMENT RESPONDING TO FEBRUARY 26, 2004 OFFICE ACTION IN U.S.  
PATENT APPLICATION NO. 09/954,831 AND PETITION FOR EXTENSION OF TIME  
UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

This responds to the February 26, 2004 Office Action in the above-identified application. Please amend the application as set out in the following Section I (Amendment of the Claims). Remarks addressing the substance of the February 17, 2004 Office Action are set out in Section II (Remarks) hereof.